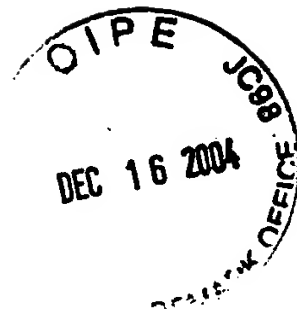


00862.022246



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
	: Examiner: H. Nguyen
Kazunori IWAMOTO et al.)
	: Group Art Unit: 2851
Application No.: 09/866,600)
	: Confirmation No.: 4961
Filed: May 30, 2001)
	: Allowed: October 14, 2004
For: STAGE APPARATUS WHICH SUPPORTS)
INTERFEROMETER, STAGE POSITION	: December 16, 2004
MEASUREMENT METHOD, PROJECTION)
EXPOSURE APPARATUS, PROJECTION	:
EXPOSURE APPARATUS MAINTENANCE)
METHOD, SEMICONDUCTOR DEVICE	:
MANUFACTURING METHOD, AND)
SEMICONDUCTOR MANUFACTURING	:
FACTORY)

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

LETTER TRANSMITTING CORRECTED FORMAL DRAWINGS

Sir:

Transmitted herewith are two (2) formal drawing sheets, corrected Figs. 5 and 6, to be substituted for the corresponding drawing sheet currently on file in the above-identified application.

Figures 5 and 6 incorporate the changes requested by Applicants in a Request for Approval of Drawing Changes filed August 30, 2003, which were subsequently approved by the Examiner in the Notice of Allowability dated October 14, 2004.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address listed below.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "Steven E. Warner", written over a horizontal line.

Attorney for Applicants

Steven E. Warner

Registration No. 33,326

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